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APPLICATION NO.	FILING DATE	FIRST NAMED INVENTOR	ATTORNEY DOCKET NO.	CONFIRMATION NO.
09/917,549	07/27/2001	Harald Richter	W&B-INF-701	4007
24131 75	90 10/17/2005		EXAMINER	
LERNER AND GREENBERG, PA			OLSEN, ALLAN W	
P O BOX 2480 HOLLYWOOD, FL 33022-2480			ART UNIT	PAPER NUMBER
	,		1763	•

DATE MAILED: 10/17/2005

Please find below and/or attached an Office communication concerning this application or proceeding.

		<i>(</i>			
	Application No.	Applicant(s)			
	09/917,549	RICHTER ET AL.			
Office Action Summary	Examiner	Art Unit			
	Allan Olsen	1763			
<ul> <li> The MAILING DATE of this communication app</li> <li>Period for Reply</li> </ul>	ears on the cover sheet with the c	orrespondence address			
A SHORTENED STATUTORY PERIOD FOR REPLY THE MAILING DATE OF THIS COMMUNICATION.  - Extensions of time may be available under the provisions of 37 CFR 1.13 after SIX (6) MONTHS from the mailing date of this communication.  - If the period for reply specified above is less than thirty (30) days, a reply - If NO period for reply is specified above, the maximum statutory period w - Failure to reply within the set or extended period for reply will, by statute, - Any reply received by the Office later than three months after the mailing earned patent term adjustment. See 37 CFR 1.704(b).  Status	iside). In no event, however, may a reply be time within the statutory minimum of thirty (30) days ill apply and will expire SIX (6) MONTHS from cause the application to become ABANDONEI	nely filed s will be considered timely. the mailing date of this communication. O (35 U.S.C. § 133).			
1) Responsive to communication(s) filed on 19 J	<u>uly 2005</u> .				
2a)⊠ This action is <b>FINAL</b> . 2b)□ Thi	s action is non-final.				
3) Since this application is in condition for allowatiosed in accordance with the practice under ADISPOSITION OF Claims					
4) Claim(s) <u>1-3,5,6 and 8-10</u> is/are pending in the	e application.				
4a) Of the above claim(s) is/are withdraw	vn from consideration.				
5) Claim(s) is/are allowed.	•				
6)⊠ Claim(s) <u>1-3,5,6 and 8-10</u> is/are rejected.					
7) Claim(s) is/are objected to.					
8) Claim(s) are subject to restriction and/or	election requirement.				
Application Papers					
9) The specification is objected to by the Examiner	<u> </u>	. <b>F</b>			
10) The drawing(s) filed on 27 July 2001 is/are: a)					
Applicant may not request that any objection to the 11) The proposed drawing correction filed on		···			
If approved, corrected drawings are required in rep		veu by the Examiner.			
12) The oath or declaration is objected to by the Exa					
Priority under 35 U.S.C. §§ 119 and 120					
13)⊠ Acknowledgment is made of a claim for foreign	priority under 35 H S C & 110/a	)-(d) or (f)			
a) ⊠ All b) □ Some * c) □ None of:	priority under 05 0.0.0. 3 115(a)	)-(u) or (i).			
1.⊠ Certified copies of the priority documents	have been received				
2. Certified copies of the priority documents have been received in Application No					
<ol> <li>Copies of the certified copies of the prior application from the International Bur</li> </ol>	ity documents have been receive eau (PCT Rule 17.2(a)).	ed in this National Stage			
* See the attached detailed Office action for a list of the certified copies not received.  14) Acknowledgment is made of a claim for domestic priority under 35 U.S.C. § 119(e) (to a provisional application).					
·					
<ul> <li>a)</li></ul>					
Attachment(s)	<b></b>	(DTO 440) D			
) ☐ Notice of References Cited (PTO-892)  Diagram Notice of Draftsperson's Patent Drawing Review (PTO-948)  Diagram Information Disclosure Statement(s) (PTO-1449) Paper No(s)		(PTO-413) Paper No(s) Patent Application (PTO-152)			

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### **DETAILED ACTION**

## Claim Rejections - 35 USC § 103

The following is a quotation of 35 U.S.C. 103(a) which forms the basis for all obviousness rejections set forth in this Office action:

(a) A patent may not be obtained though the invention is not identically disclosed or described as set forth in section 102 of this title, if the differences between the subject matter sought to be patented and the prior art are such that the subject matter as a whole would have been obvious at the time the invention was made to a person having ordinary skill in the art to which said subject matter pertains. Patentability shall not be negatived by the manner in which the invention was made.

Claims 1-3, and 5, 6 and 8-10 are rejected under 35 U.S.C. 103(a) as being unpatentable over US Patent 6,080,529 issued to Ye et al. (hereinafter, Ye) in view of U.S. Patent 5,986,344 issued to Subramanion et al. (hereinafter, Subramanion)

Ye teaches a method of anisotropically etching interfacial organic polymer layers. Ye teaches that the preferred etchant consists of hydrogen and nitrogen, however, Ye also teaches that additives may be included to improve the etching profile or to control residue (column 20, lines 46-67). Ye teaches etching low k dielectric materials such as SiLK, FLARE and BCB (column 19, lines 52-58; column 23, lines 5-24). Ye teaches that an underlying layer of silicon dioxide or tantalum nitride functions as etch stop layer when an overlying organic layer is etched (column 12, lines 38-42). Ye teaches that straight sidewalls are obtained when etching the organic material with the nitrogen/hydrogen plasma (column 22, lines 56-58).

Ye does not teach using FLARE as an ARC or that the polymeric organic interfacial layer being etched functions as an ARC.

Subramanion teaches that FLARE functions as an ARC. Subramanion teaches providing an organic-ARC layer over a layer of SiO<sub>2</sub>.

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It would have been obvious to one skilled in the art to provide a layer of FLARE between the photoresist and SiO<sub>2</sub> of Ye because Ye teaches that using an ARC improves the resolution of a pattern and Subramanion teaches that FLARE is useful as an ARC when the FLARE is interdisposed between a layer of photoresist and a layer of SiO<sub>2</sub>.

With respect to the 1:50 selectivity, the examiner notes Ye's teaching that silicon dioxide functions as an etch stop (i.e., selectivity  $\rightarrow \infty$ ) when an overlying organic material is etched. Furthermore, Ye and Subramanion make applicant's claimed invention obvious. As such, when conducting the method made obvious by Ye and Subramanion, the skilled artisan, is expected to achieve results that are commensurate with those of the claimed invention. For, example, when conducting the method made obvious by Ye and Subramanion, the skilled artisan, is expected to realize etching rates such that the rate of vertical removal of the photoresist is less than the vertical removal rate of the antireflection layer.

Ye does not teach using a MERIE, ECR, ICP or helicon plasma apparatus.

It would be obvious to one skilled in the art to use a MERIE, ECR, ICP or helicon plasma apparatus because each of these apparatus are known for providing a higher density plasma which provides for faster etching rates and high etching selectivity, as well as the ability to use a lower plasma source power which in turn reduces plasma damage to the workpiece.

In regards to the limitations that pertain to process conditions such as flow rates, chamber pressure and magnetic field strength, it is noted that process parameters such

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as these are considered to be cause effective variables, which may be optimized through routine experimentation. As such, claims to specific values of such parameters cannot provide the basis for patentablity.

"Normally, it is to be expected that a change in temperature, or in concentration, or in both, would be an unpatentable modification. Under some circumstances, however, changes such as these may impart patentability to a process if the particular ranges claimed produce a new and unexpected result which is different in kind and not merely degree from the results of the prior art... such ranges are termed "critical ranges and the applicant has the burden of proving such criticality... More particularly, where the general conditions of a claim are disclosed in the prior art, it is not inventive to discover the optimum or workable ranges by routine experimentation."

In re Aller 105 USPQ 233, 255 (CCPA 1955). See also In re Waite 77 USPQ 586 (CCPA 1948); In re Scherl 70 USPQ 204 (CCPA 1946); In re Irmscher 66 USPQ 314 (CCPA 1945); In re Norman 66 USPQ 308 (CCPA 1945); In re Swenson 56 USPQ 372 (CCPA 1942); In re Sola 25 USPQ 433 (CCPA 1935); In re Dreyfus 24 USPQ 52 (CCPA 1934).

## Response to Arguments

Applicant's arguments filed July 19, 2005 have been fully considered but they are not persuasive. Applicant argues that neither Ye nor Subramanion teach a gas composition that results in the rate of vertical removal of the photoresist to correspond at most to the vertical removal rate of the antireflection layer. The limitation upon which applicant relies finds support in original claim 7. Applicant's have cancelled claim 7 and have incorporated the limitation of original claim 7 into claim 1. Additionally, applicant expresses the opinion that the examiner did not offer any reason why claim 7 was rejected.

The rejection of claim 1 now includes a more explicit reference to the limitation of original claim 7.

"Furthermore, Ye and Subramanion make applicant's claimed invention obvious. As such, when conducting this method made obvious by Ye and Subramanion, the skilled artisan, is expected to achieve results that are commensurate with those of

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claimed invention. <u>For, example, when conducting the method made obvious by Ye</u> and Subramanion, the skilled artisan, is expected to realize etching rates such that the rate of vertical removal of the photoresist is less than the vertical removal rate of the antireflection layer."

However, the statement in the Office action of April 19, 2005 is considered to have addressed the issue of claim 7, especially considering the fact that the statement was made in the context of addressing relative etching rates, which is the same issue that is raised by original claim 7.

#### Conclusion

THIS ACTION IS MADE FINAL. Applicant is reminded of the extension of time policy as set forth in 37 CFR 1.136(a).

A shortened statutory period for reply to this final action is set to expire THREE MONTHS from the mailing date of this action. In the event a first reply is filed within TWO MONTHS of the mailing date of this final action and the advisory action is not mailed until after the end of the THREE-MONTH shortened statutory period, then the shortened statutory period will expire on the date the advisory action is mailed, and any extension fee pursuant to 37 CFR 1.136(a) will be calculated from the mailing date of the advisory action. In no event, however, will the statutory period for reply expire later than SIX MONTHS from the mailing date of this final action.

Any inquiry concerning this communication or earlier communications from the examiner should be directed to Allan Olsen whose telephone number is 571-272-1441. The examiner can normally be reached on M-F 1-5.

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If attempts to reach the examiner by telephone are unsuccessful, the examiner's supervisor, Parviz Hassanzadeh can be reached on 571-272-1435. The fax phone number for the organization where this application or proceeding is assigned is 703-872-9306.

Information regarding the status of an application may be obtained from the Patent Application Information Retrieval (PAIR) system. Status information for published applications may be obtained from either Private PAIR or Public PAIR. Status information for unpublished applications is available through Private PAIR only. For more information about the PAIR system, see http://pair-direct.uspto.gov. Should you have questions on access to the Private PAIR system, contact the Electronic Business Center (EBC) at 866-217-9197 (toll-free).

Ma Obe

Allan Olsen
Primary Examiner

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